

TECHNICAL SPECIFICATION



**Nanomanufacturing – Key control characteristics –
Part 5-4: Energy band gap measurement of nanomaterials by electron energy
loss spectroscopy (EELS)**

INTERNATIONAL
ELECTROTECHNICAL
COMMISSION

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INTERNATIONAL ELECTROTECHNICAL COMMISSION

NANOMANUFACTURING – KEY CONTROL CHARACTERISTICS –**Part 5-4: Energy band gap measurement of nanomaterials
by electron energy loss spectroscopy (EELS)**

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Draft	Report on voting
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Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this Technical Specification is English.

This document was drafted in accordance with ISO/IEC Directives, Part 2, and developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC Supplement, available at www.iec.ch/members_experts/refdocs. The main document types developed by IEC are described in greater detail at www.iec.ch/publications.

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The committee has decided that the contents of this document will remain unchanged until the stability date indicated on the IEC website under webstore.iec.ch in the data related to the specific document. At this date, the document will be

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INTRODUCTION

Electronic and electrical devices developed up to now have been fabricated by stacking a series of active and/or passive layers on a specific substrate. The current trend in developing such devices is the miniaturization of product size, whereas the basic structure of multilayers on a substrate has not changed. Accordingly geometrical scales in the inner structure of a device have been decreasing and some of the scales such as thickness of the layers have finally reached a few nanometres. One of the key control characteristics (KCCs) is the band gap of an active layer which enables the electron or hole transportation, excitation and emission of electrons, etc. to be controlled.

The band gap is referred to as an energy gap, which means a difference between an energy level in which electrons exist and an energy level in which electrons do not exist. Even though the band gap of a material is intrinsic, the band gap of a nanomaterial is an extrinsic property which represents its size-dependency. Therefore, the band gap of nanoscale materials needs to be measured locally, in situ or in vitro.

For the band gap measurement application to nanomaterials, a specific region of a nanometre-scale device or a single layer of the multi-layered structure, a transmission electron microscope (TEM), which has atomic-scale image resolution, and electron energy loss spectroscopy (EELS), which can measure energy loss of electrons, have in general been used.

In this document, a method of measuring the band gap energy at a specific location for a nanomaterial by using TEM and EELS is proposed.

NANOMANUFACTURING – KEY CONTROL CHARACTERISTICS –

Part 5-4: Energy band gap measurement of nanomaterials by electron energy loss spectroscopy (EELS)

1 Scope

This part of IEC TS 62607 specifies the measuring method of the band gap energy of a nanomaterial using electron energy loss data of transmission electron microscope.

The method specified in this document is applicable to semiconducting and insulating nanomaterials to estimate the band gap.

The measurement to get reliable data is performed under the consistent conditions of TEM observation and specimen thickness. The applicable measurement range of band gap energy is more than 2 eV.

2 Normative references

There are no normative references in this document.